

ABSTRACT

To provide a form variable mirror element and a form variable mirror unit which are extremely thin with a simple structure and large in an amount of deformation even under low applied voltage, a form variable mirror element comprising: a form variable part including a piezoelectric film, a first electrode film and a second electrode film for supplying voltage to the piezoelectric film and a reflection mirror film provided in the piezoelectric film; and a base for supporting the form variable part. The form variable part is provided with an elastic unit for giving elasticity to the form variable part. Thus, the films are laminated on the thin base by a thin film forming technique. Accordingly, the extremely thin form variable mirror element can be formed with a simple structure, so that a large amount of deformation can be effectively obtained even when low voltage is applied.